

INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)				Docket Number (Optional)		Application Number			
				FIS920030301		20920773			
				Applicant(s)				Beaman, et al.	
				Filing Date		Group Art Unit			
08/27/04		2833							
U.S. PATENT DOCUMENTS									
EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE		
<i>LT</i>		6,452,406	09/17/2003	Beaman, et al.					
<i>LT</i>		6,438,584	03/04/2003	Beaman, et al.					
U.S. PATENT APPLICATION PUBLICATIONS									
EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE		
FOREIGN PATENT DOCUMENTS									
REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation YES NO			
OTHER DOCUMENTS (Including Author, Title, Date, Foreign Patent, Etc.)									
JMH	<i>LT</i>	US Application: 09/134/769 Title: Wafer Scale High Density Probe Assembly, Apparatus For Use Thereof And Methods Of Fabrication Thereof Filing Date: 03/11/1999 Name: Lauro, et al.							
JMH	<i>LT</i>	US Application: 08/732/831 Title: High Temperature Chip Test Probe Filing Date: 11/10/1996 Name: Lauro, et al.							
EXAMINER				DATE CONSIDERED					
<i>Jerome Hollington</i>				<i>08/25/05</i>					
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.									

Form PTO-A820
(also form PTO-1443)

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